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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2822

Examiner: Kevin M. Picardat

In re PATENT APPLICATION of

Applicant(s) : Junichi HIKITA et al.

Appl. No. : 10/748,327

Filed : December 31, 2003

For : PRODUCTION PROCESS FOR
SEMICONDUCTOR DEVICE

Allowed : October 6, 2005

Atty. Dkt. : AI 258 D1

CITATION OF
PRIOR ART

Mail Stop: Issue Fee

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This is citation of prior art submitted after a Notice of Allowance and payment of the issue fee.

Attached is a copy of one Japanese Unexamined Patent Publication and its English abstract. Also attached is a copy of Japanese Unexamined Patent Publication No. 5-206143 with its corresponding EP 0 544 305 A2. The Japanese Patent Publications were cited in an attached Japanese Office Action dated January 31, 2006 issued in connection with a counterpart Japanese application No. 11-45214. A form PTO-1449 listing the references is attached as well.

It is requested that this Citation of Prior Art simply be placed in the PTO file for this application. Therefore no fee is required and none is submitted.

Respectfully submitted,

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February 10, 2006

Date

SMR:pjl



FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT				Atty. Docket AI 258D1		Divisional Application No. 10/748,327	
				Applicant Junichi HIKITA et al.			
				Filing Date December 31, 2003		Group 2822	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub-Class	Translation
	AI	06-084922	03/25/94	Japan			Abstract
	AJ	05-206143	08/13/93	Japan			Abstract
	AK	0 544 305	06/02/93	Europe			
	AL						
	AM						
	AN						
OTHER (Including Author, Title, Date, Pertinent Pages, etc.)							
	AO						
Examiner					Date Considered		
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							